



RECEIVED

AUG 09 2001

Sheet 1 of 2

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE

ATTY. DOCKET NO.
ONX-109SERIAL NO.
09/712,420LIST OF PRIOR ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Michael J. Daneman, Behrang BehrangFILING DATE
11/13/2000GROUP
Not yet assigned

U.S. PATENT DOCUMENTS

EXAMINE R INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
RC	A	5 6 4 5 6 8 4	7/8/97	Keller	156	643.1	6/7/1995
	B	5 7 1 7 6 3 1	2/10/98	Carley et al.	365	174	6/25/1995
	C	5 9 0 8 7 1 9	6/1/99	Guckel et al.	430	5	9/11/1998
	D	5 9 7 1 3 5 5	10/26/99	Biegelsen et al.	251	129.06	11/27/1996
	E	5 9 4 9 5 7 1	9/7/99	Goossen et al.	359	291	7/30/1998
	F	5 9 4 3 1 5 5	8/24/99	Goossen	359	247	8/12/1998
	G	5 8 6 6 2 8 1	2/2/99	Guckel et al.	430	22	11/27/1996
	H	5 6 3 8 9 4 6	6/17/97	Zavracky	200	181	1/11/1996
	I	5 6 3 7 5 3 9	6/10/97	Hofmann et al.	438	20	1/16/1996
	J	5 3 2 7 0 3 3	7/5/94	Guckel et al.	310	40	12/30/1992
	K	5 2 0 6 9 8 3	5/4/93	Guckel et al.	29	598	5/24/1991
	L	5 0 4 3 0 4 3	8/27/91	Howe et al.	21	306	6/22/1990
	M	5 9 1 4 5 0 7	6/22/99	Polla et al.	257	254	10/30/1996
	N	6 0 2 5 9 5 1	2/15/00	Swart et al.	359	245	11/27/1996
	O	5 3 1 4 5 7 2	5/24/94	Core et al.	156	643	4/22/1992
	P	6 2 0 3 7 1 5	3/20/01	Kim et al.	216	24	1/19/1999
	Q	6 0 2 1 6 7 5	2/8/2000	Sefeldt et al.	73	777	2/28/1997
	R	5 5 7 6 2 5 0	11/19/1996	Diem et al.	437	228	12/27/1993
RC	S	5 7 8 0 8 8 5	7/14/1998	Diem et al.	257	254	8/15/1996

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLA SS	TRANSLATION	
							YES	NO
RC	T	1 0 3 3 6 0 1	6/9/2000	Europe	G02B	26/02		X
	U	2 3 2 1 7 8 0	8/5/1998	Great Britain	H01L	37/02		X
	V	0 6 0 5 3 0 0	7/6/1994	Europe	G01P	15/08		X
RC	W	0 9 4 2 4 6 2	9/15/1999	Europe	H01L	21/311		X
								X



OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
<i>M</i>	X	Yao et al., "Single Crystal Silicon Supported Thin Film Micro Mirrors for Optical Applications" Opt. Eng. 36(5) 1408-1413 (May 1997)
<i>M</i>	Y	Conant et al. "A Flat High Frequency Scanning Micromirror" Abstract Submitted to Hilton Head 2000
<i>M</i>	Z	Storment et al. "Flexible Dry Release Process for Aluminum Electrostatic Actuators" Journal of Microelectromechanical System Vol. 3 No. 3 Sept 1994
<i>M</i>	AA	Mita et al., "An Out-of-Plane Polysilicon Actuator With a Smooth Vertical Mirror for Optical Fiber Switch Application"
<i>M</i>	AB	Marxer et al. "Vertical Mirrors Fabricated by Deep Reactive Ion Etching For Fiber-Optic Switching Applications" Journal of Microelectromechanical Systems, Vol. 6 No. 3, Sept 1997
<i>M</i>	AC	Fedder, G.K., "integrated microelectromechanical systems in conventional CMOS", Proceedings of 1997 IEEE International Symposium on Circuits and Systems. Circuits and Systems in the Information Age. ISCAS '97 (Cat. No. 97CH35987), pages 2821-2824, vol. 4
EXAMINER <i>Robert Gilbert</i>		DATE CONSIDERED <i>10/21/02</i>
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		

RECEIVED
AUG 21 2001
USPTO